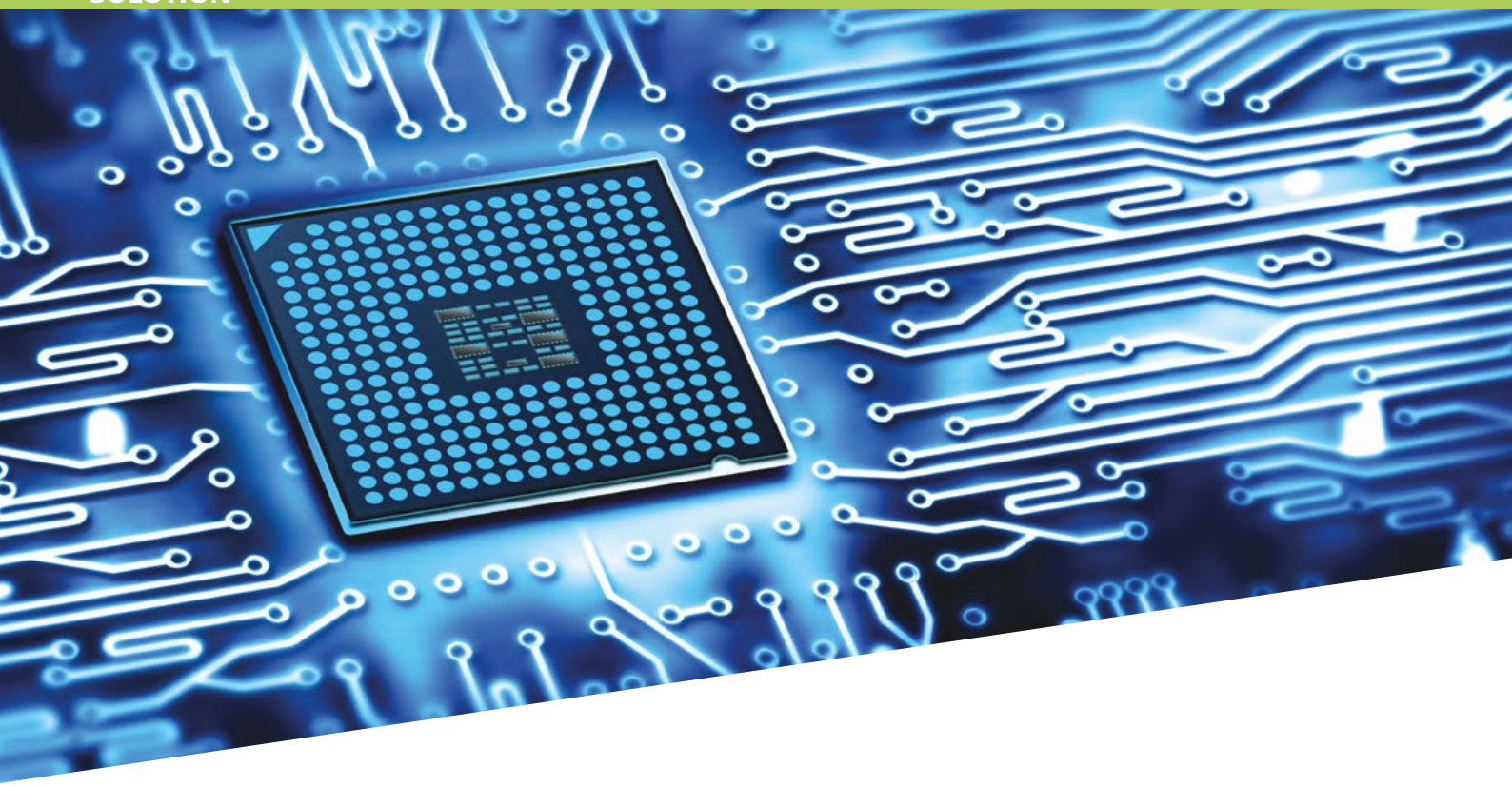
Dependable Products to Optimize Your Fabrication Yield Rates

Fluid Control and Pneumatic Solutions for the Semiconductor Industry

SOLUTION



Ensure Chip Performance and Reliability in Clean Environments

Ideal for critical semiconductor applications, Emerson fluid control and pneumatic components and systems ensure high process purity and precision with minimal media contamination in cleanrooms — boosting your throughput and optimizing your fabrication yield rates.

- Emerson fluid control and pneumatic products offer high degrees of performance and dependability, boosting the overall reliability of the chip-making process.
- Products deliver superior performance even in the presence of specialty gases, reducing your maintenance needs and minimizing production downtime.
- Equipped with IIoT capabilities, these products enable temperature, flow, pressure and position control with greater precision and energy efficiency.

EMERSON™

CONSIDER IT SOLVED™

Product Selection

AVENTICS™ Pneumatic Control and Manifold Solutions

- Designed for IIoT applications
- Ideal for various applications — e.g. compact handling systems
- Provide consistent communication to the valve and integrated web server

ASCO™ and AVENTICS™ Proportional Control Valves

- Regulate the variable flow of air and gases
- Deliver responsive, precise flow control, compensating for control chain changes
- Provide optimal pressure control within many machines and processes worldwide
- Feature a small footpoint and broad range of connection options

ASCO™ Cryogenic Valves

- Developed for high-performance fluorinated fluids and supports a wide range of temperatures
- Suitable for use in chillers and temperature control devices

ASCO™ General Service Valves

- Support various media
- Rugged and reliable, with two-way solenoid technology
- Can be quickly sized according to application requirements

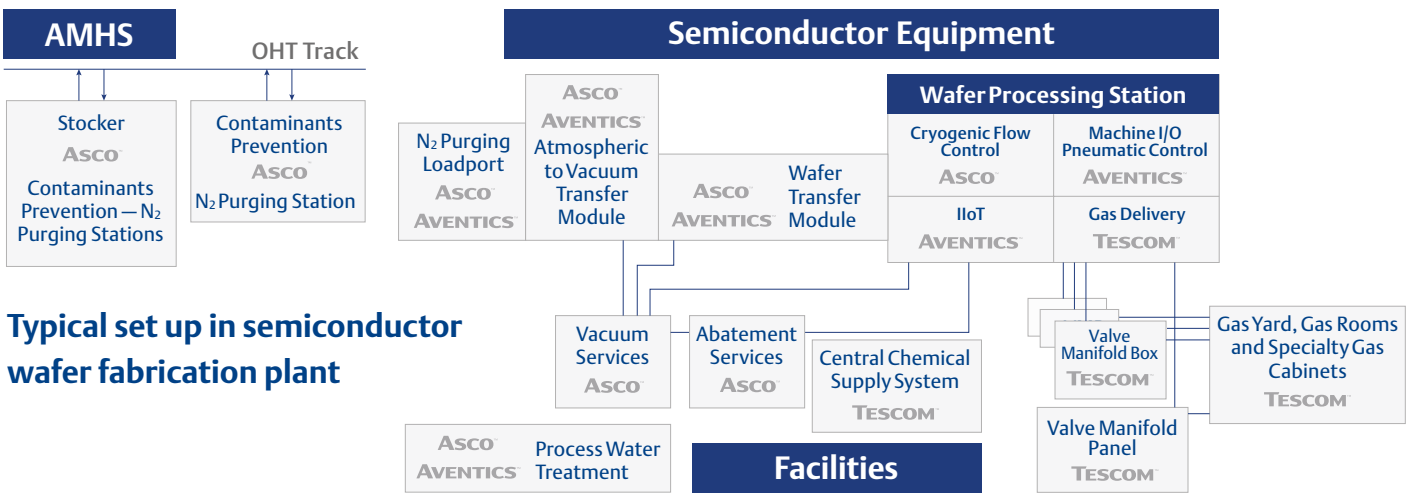
TESCOM™ Pressure Control Solutions

- Maintain and control pressure with accuracy, precision and stability across many flows
- Integrate ultra high-purity designs that avoid contamination and prevent wafer and chip failure during the fabrication process

TESCOM™ Changeover and Electropneumatic Controllers

- Microprocessor based closed-loop PID controller
- Fully automates any TESCOM regulator
- Delivers 0.1% accuracy with 25 ms response time, data acquisition, and remote control capabilities
- Changeover system ensures continuous supply of process gas

Emerson's Solutions Offerings



Typical set up in semiconductor wafer fabrication plant

For more information:
www.Emerson.com/Semiconductor

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